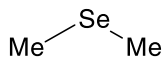


Catalog # 34-0550 Dimethylselenide (99.99+%-Se) PURATREM



Thermal Behavior:

- Melting point: -87.2°C
- Boiling point: 57-58°C
- Vapor pressure: 240 Torr/25°C [1]

Technical Notes:

1. ALD/CVD precursor for selenide thin film deposition.

Target Deposit	Deposition Technique	Delivery Temperature	Pressure	Co-reactants	Deposition Temperature	Ref.
GeSe ₂	PECVD	-	2.5 Torr	GeCl ₄ , H ₂	125-140°C	2-3
WSe ₂	CVD	23°C	-	W(CO) ₆	600-900°C	4-5

References:

1. [J. Chem. Eng. Data **1994**, *39*, 608.](#)
2. [Plasma Chem. Plasma Process **2011**, *31*, 251.](#)
3. [Plasma Chem. Plasma Process **2014**, *34*, 755.](#)
4. [ACS Nano, **2015**, *9*, 2080.](#)
5. [J. Electron. Mater. **2016**, *45*, 6273.](#)